Pressure Dependence of Resistance of Germanium

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Citation Report

#	Article	IF	CITATIONS
1	Temperature Dependence of the Energy Gap in Semiconductors. Physical Review, 1951, 82, 900-905.	2.7	531
2	Effect of Temperature on the Height of Potential Barriers and on the Breakdown Voltage of Contact Rectifiers. Proceedings of the Physical Society Section A, 1951, 64, 752-753.	1.1	2
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4	The Electrical Conductance of Pressed Powders, in Particular of Zinc Oxide. Physical Review, 1954, 94, 56-60.	2.7	22
5	Piezoresistance Effect in Germanium and Silicon. Physical Review, 1954, 94, 42-49.	2.7	1,735
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7	Piezoresistance Constants of P-Type InSb. Physical Review, 1958, 109, 1980-1987.	2.7	22
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10	Physics at High Pressure. Solid State Physics, 1960, 11, 41-147.	0.5	23
11	The Parameters of the 0.099-eV Neutron Resonance in Sm-149. Journal of the Physical Society of Japan, 1969, 26, 225-232.	1.6	5
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13	Direct correlation between ferrite microstructure and electrical resistivity. Journal of Applied Physics, 2007, 101, 104912.	2.5	12
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